

Part 63, Subpt. AAAAA, Table 8

40 CFR Ch. I (7-1-10 Edition)

TABLE 8 TO SUBPART AAAAA OF PART 63—APPLICABILITY OF GENERAL PROVISIONS TO SUBPART AAAAA

As required in §63.7140, you must comply with the applicable General Provisions requirements according to the following table:

Citation	Summary of requirement	Am I subject to this requirement?	Explanations
§ 63.1(a)(1)–(4)	Applicability	Yes.	§§ 63.7081 and 63.7142 specify additional applicability determination requirements.
§ 63.1(a)(5)		No.	
§ 63.1(a)(6)	Applicability	Yes.	
§ 63.1(a)(7)–(a)(9)		No.	
§ 63.1(a)(10)–(a)(14)	Applicability	Yes.	
§ 63.1(b)(1)	Initial Applicability Determination.	Yes	
§ 63.1(b)(2)		No.	
§ 63.1(b)(3)	Initial Applicability Determination.	Yes.	
§ 63.1(c)(1)	Applicability After Standard Established.	Yes.	
§ 63.1(c)(2)	Permit Requirements	No	
§ 63.1(c)(3)		No.	Additional definitions in § 63.7143.
§ 63.1(c)(4)–(5)	Extensions, Notifications	Yes.	
§ 63.1(d)		No.	
§ 63.1(e)	Applicability of Permit Program.	Yes.	
§ 63.2	Definitions		
§ 63.3(a)–(c)	Units and Abbreviations	Yes.	
§ 63.4(a)(1)–(a)(2)	Prohibited Activities	Yes.	
§ 63.4(a)(3)–(a)(5)		No.	
§ 63.4(b)–(c)	Circumvention, Severability	Yes.	
§ 63.5(a)(1)–(2)	Construction/Reconstruction	Yes.	
§ 63.5(b)(1)	Compliance Dates	Yes.	
§ 63.5(b)(2)		No.	
§ 63.5(b)(3)–(4)	Construction Approval, Applicability.	Yes.	
§ 63.5(b)(5)		No.	
§ 63.5(b)(6)	Applicability	Yes.	
§ 63.5(c)		No.	
§ 63.5(d)(1)–(4)	Approval of Construction/Reconstruction.	Yes.	
§ 63.5(e)	Approval of Construction/Reconstruction.	Yes.	
§ 63.5(f)(1)–(2)	Approval of Construction/Reconstruction.	Yes.	
§ 63.6(a)	Compliance for Standards and Maintenance.	Yes.	
§ 63.6(b)(1)–(5)	Compliance Dates	Yes.	
§ 63.6(b)(6)		No.	
§ 63.6(b)(7)	Compliance Dates	Yes.	
§ 63.6(c)(1)–(2)	Compliance Dates	Yes.	
§ 63.6(c)(3)–(c)(4)		No.	
§ 63.6(c)(5)	Compliance Dates	Yes.	
§ 63.6(d)		No.	
§ 63.6(e)(1)	Operation & Maintenance	Yes	See § 63.7100 for OM&M requirements.
§ 63.6(e)(2)		No.	
§ 63.6(e)(3)	Startup, Shutdown Malfunction Plan.	Yes.	
§ 63.6(f)(1)–(3)	Compliance with Emission Standards.	Yes.	
§ 63.6(g)(1)–(g)(3)	Alternative Standard	Yes.	
§ 63.6(h)(1)–(2)	Opacity/VE Standards	Yes.	
§ 63.6(h)(3)		No.	
§ 63.6(h)(4)–(h)(5)(i)	Opacity/VE Standards	Yes	This requirement only applies to opacity and VE performance checks required in Table 4 to subpart AAAAA.

Environmental Protection Agency

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Citation	Summary of requirement	Am I subject to this requirement?	Explanations		
§ 63.6(h)(5) (ii)–(iii)	Opacity/VE Standards	No	Test durations are specified in subpart AAAAA; subpart AAAAA takes precedence.		
§ 63.6(h)(5)(iv)	Opacity/VE Standards	No.			
§ 63.6(h)(5)(v)	Opacity/VE Standards	Yes.			
§ 63.6(h)(6)	Opacity/VE Standards	Yes.			
§ 63.6(h)(7)	COM Use	Yes.			
§ 63.6(h)(8)	Compliance with Opacity and VE.	Yes.			
§ 63.6(h)(9)	Adjustment of Opacity Limit	Yes.			
§ 63.6(i)(1)–(i)(14)	Extension of Compliance	Yes.			
§ 63.6(i)(15)	Extension of Compliance	No.			
§ 63.6(i)(16)	Extension of Compliance	Yes.			
§ 63.6(j)	Exemption from Compliance	Yes.	§ 63.7110 specifies deadlines; § 63.7112 has additional specific requirements.		
§ 63.7(a)(1)–(a)(3)	Performance Testing Requirements.	Yes			
§ 63.7(b)	Notification	Yes.			
§ 63.7(c)	Quality Assurance/Test Plan	Yes.			
§ 63.7(d)	Testing Facilities	Yes.			
§ 63.7(e)(1)–(4)	Conduct of Tests	Yes.			
§ 63.7(f)	Alternative Test Method	Yes.			
§ 63.7(g)	Data Analysis	Yes.			
§ 63.7(h)	Waiver of Tests	Yes.			
§ 63.8(a)(1)	Monitoring Requirements	Yes		See § 63.7113.	
§ 63.8(a)(2)	Monitoring	Yes.	Flares not applicable.		
§ 63.8(a)(3)	Monitoring	No.			
§ 63.8(a)(4)	Monitoring	No			
§ 63.8(b)(1)–(3)	Conduct of Monitoring	Yes.			
§ 63.8(c)(1)–(3)	CMS Operation/Maintenance	Yes.			
§ 63.8(c)(4)	CMS Requirements	No			
§ 63.8(c)(4)(i)–(ii)	Cycle Time for COM and CEMS.	Yes		See § 63.7121. No CEMS are required under subpart AAAAA; see § 63.7113 for CPMS requirements.	
§ 63.8(c)(5)	Minimum COM procedures	Yes		COM not required.	
§ 63.8(c)(6)	CMS Requirements	No		See § 63.7113.	
§ 63.8(c)(7)–(8)	CMS Requirements	Yes.		See § 63.7113.	
§ 63.8(d)	Quality Control	No			
§ 63.8(e)	Performance Evaluation for CMS.	No.			
§ 63.8(f)(1)–(f)(5)	Alternative Monitoring Method	Yes.			
§ 63.8(f)(6)	Alternative to Relative Accuracy test.	No.			
§ 63.8(g)(1)–(g)(5)	Data Reduction; Data That Cannot Be Used.	No	See data reduction requirements in §§ 63.7120 and 63.7121.		
§ 63.9(a)	Notification Requirements	Yes	See § 63.7130.		
§ 63.9(b)	Initial Notifications	Yes.			
§ 63.9(c)	Request for Compliance Extension.	Yes.			
§ 63.9(d)	New Source Notification for Special Compliance Requirements.	Yes.			
§ 63.9(e)	Notification of Performance Test.	Yes.			
§ 63.9(f)	Notification of VE/Opacity Test.	Yes		This requirement only applies to opacity and VE performance tests required in Table 4 to subpart AAAAA. Notification not required for VE/opacity test under Table 6 to subpart AAAAA.	
§ 63.9(g)	Additional CMS Notifications	No			Not required for operating parameter monitoring.
§ 63.9(h)(1)–(h)(3)	Notification of Compliance Status.	Yes.			
§ 63.9(h)(4)	Notification of Compliance Status.	No.			
§ 63.9(h)(5)–(h)(6)	Notification of Compliance Status.	Yes.			
§ 63.9(i)	Adjustment of Deadlines	Yes.			
§ 63.9(j)	Change in Previous Information.	Yes.			

Citation	Summary of requirement	Am I subject to this requirement?	Explanations
§ 63.10(a)	Recordkeeping/Reporting General Requirements.	Yes	See §§ 63.7131 through 63.7133.
§ 63.10(b)(1)–(b)(2)(xii)	Records	Yes.	
§ 63.10(b)(2)(xiii)	Records for Relative Accuracy Test.	No.	See § 63.7132.
§ 63.10(b)(2)(xiv)	Records for Notification	Yes.	
§ 63.10(b)(3)	Applicability Determinations	Yes.	See § 63.7132.
§ 63.10(c)	Additional CMS Recordkeeping.	No	
§ 63.10(d)(1)	General Reporting Requirements.	Yes.	For the periodic monitoring requirements in Table 6 to subpart AAAAA, report according to § 63.10(d)(3) only if VE observed and subsequent visual opacity test is required.
§ 63.10(d)(2)	Performance Test Results	Yes.	
§ 63.10(d)(3)	Opacity or VE Observations	Yes	
§ 63.10(d)(4)	Progress Reports	Yes.	See specific requirements in subpart AAAAA, see § 63.7131.
§ 63.10(d)(5)	Startup, Shutdown, Malfunction Reports.	Yes.	
§ 63.10(e)	Additional CMS Reports	No	Flares not applicable.
§ 63.10(f)	Waiver for Recordkeeping/Reporting.	Yes.	
§ 63.11(a)–(b)	Control Device Requirements	No	Flares not applicable.
§ 63.12(a)–(c)	State Authority and Delegations.	Yes.	
§ 63.13(a)–(c)	State/Regional Addresses	Yes.	
§ 63.14(a)–(b)	Incorporation by Reference	No.	
§ 63.15(a)–(b)	Availability of Information	Yes.	

**Subpart BBBB—National Emission Standards for Hazardous Air Pollutants for Semiconductor Manufacturing**

SOURCE: 68 FR 27925, May 22, 2003, unless otherwise noted.

**WHAT THIS SUBPART COVERS**

**§ 63.7180 What is the purpose of this subpart?**

This subpart establishes national emission standards for hazardous air pollutants (NESHAP) for semiconductor manufacturing facilities. This subpart also establishes requirements to demonstrate initial and continuous compliance with the emission standards.

**§ 63.7181 Am I subject to this subpart?**

(a) You are subject to this subpart if you own or operate a semiconductor manufacturing process unit that is a major source of hazardous air pollutants (HAP) emissions or that is located

at, or is part of, a major source of HAP emissions.

(b) A major source of HAP emissions is any stationary source or group of stationary sources located within a contiguous area and under common control that emits or has the potential to emit, considering controls, in the aggregate, any single HAP at a rate of 10 tons per year (tpy) or more or any combination of HAP at a rate of 25 tpy or more.

**§ 63.7182 What parts of my facility does this subpart cover?**

(a) This subpart applies to each new, reconstructed, or existing affected source that you own or operate that manufactures semiconductors.

(b) An affected source subject to this subpart is the collection of all semiconductor manufacturing process units used to manufacture p-type and n-type semiconductors and active solid-state devices from a wafer substrate, including research and development activities integrated into a semiconductor